

Taylor Kent Templeton

1125 Ralph Drive, Cary, North Carolina, 27511 | 919.538.2666 | taylor.templeton@gmail.com

SUMMARY

Engineer with semiconductor fabrication background reskilling for an entry-level verification engineering role.

SKILLS

Projects:

- Simple CPU Verification Practice May 2023
 - https://github.com/taylor templeton/VerificationPractice_SimpleCPU
 - Drafted verification plan, created UVM testbench, and verified simple CPU and each component
 - Quantified verification with functional coverage and SystemVerilog Assertions
- Labs from Cadence Certification Training: Mar 2023
 - <https://github.com/taylor templeton/CadenceSystemVerilogTraining>
 - Projects completed while completing below cited certifications
- OoO CPU Verification Practice ECD July 2023
 - Project definition in progress. Project to include block-level verification plan and hierarchically reusable UVM/SV testbench architecture for some aspect of Berkley's OoO risc-v BOOMcore.

Certifications:

- Cadence Training Certifications:
 - SystemVerilog for Design and Verification v21.10 Exam
 - SystemVerilog Accelerated Verification with UVM v1.2.5 Exam
 - SystemVerilog Assertions v5.1 Exam
- Coursera/Duke University: Introductory C Programming Specialization

Languages: C/C++, Systemverilog

Methodologies: UVM, SVA

EXPERIENCE

Qorvo, Inc., Greensboro, NC

Customer Quality Engineer, Advanced Cellular Group Mar 2021 – Aug 2022

- Served as quality contact for multinational manufacturers purchasing Qorvo RF front end modules
- Lead cross-functional 8D investigations to investigate and resolve customer-reported quality issues

Wolfspeed (Cree), Durham, NC

RF Product Engineer II May 2019 – Mar 2021

- RF Development Team participant, tasked establishing GaN-on-SiC device production line
- Participated in production line planning, equipment purchases, product qualification

Process Engineer I; Dry and Wet Etch Sept 2018 – May 2019

- Responsible for NCM disposition, SPC monitoring and response, process improvement projects
- Solved highest yield-impacting fab defect: Si implant defectivity caused by operator mishandling

Process Engineering Technician III; Metal, Dielectric, Etch July 2015 – Sept 2018

- Investigated tool failures, product anomalies, misprocess events
- Supported sputter, evaporation, bond, anneal, dry etch, wet etch, and CVD process areas

EDUCATION

New York University, New York, NY

Sept 2012 – May 2015

B.S., Chemical and Biomolecular Engineering, magna cum laude, 3.64 GPA

University Honors Scholar, Tau Beta Pi Honor Society, Omega Chi Epsilon Chemical Engineering Honor Society

PERSONAL INTERESTS

I enjoy reading about history, fitness, and working on my house, which refuses to stop slowly falling apart.